

### **In the Specification**

At page 1, lines 7– 17, please replace the paragraph as follows (underlined denotes replacements additions and strikethough notes deletions):

Systems which handle material, such as manufacturing facilities, often employ automated material handling systems to move various materials from one location to [[a]] another location within the system. The materials may include raw materials, finished product materials, or any materials in between. It is common to employ containers or carriers to move the materials from one location to another during the manufacturing process. Typically, a transportation system is employed, such as a conveyor belt system, for moving the carriers from one processing location to another within the system. Typically, empty containers are needed at the various process locations for holding processed materials. Likewise, empty carriers are generated as material is removed from a carrier in order to be processed. Empty containers may also be added or removed from the system.

At page 5, lines 15– 22, please replace the paragraph as follows (underlined denotes replacements additions and strikethough notes deletions):

It should be appreciated that these attributes are exemplary only and may or may not be used in a given environment. Other and/or additional attributes may also be provided to classify the wafer carriers. In addition, the attributes of a carrier may change depending on the wafers held by a carrier during its use. A more detailed discussion of attribute handling may be found in U.S. Patent Application Serial No. 09/193,349, entitled “Managing A Semiconductor Fabrication Facility Using Water Lot And Cassette Attributes”, filed on November 17, 1998, now U.S. Patent No. 6,449,552, the contents of which are herein incorporated by reference.